



# Electronic Filing System (EFS) Data

## Electronic Patent Application Submission

### USPTO Use Only

EFS ID: 56108

Application ID: 10672298



Title of Invention:  
METHOD AND APPARATUS USING  
INTERFEROMETRIC METROLOGY  
FOR HIGH ASPECT RATIO  
INSPECTION

First Named Inventor: Shiow-Hwei Hwang

Domestic/Foreign Application: Domestic Application

Filing Date: 2004-02-25

Effective Receipt Date: 2004-02-25

Submission Type:  
Information Disclosure  
Statement

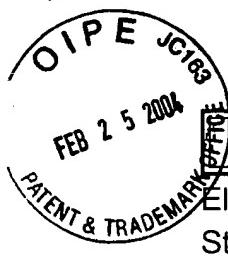
Filing Type:

Confirmation number: 4459

Attorney Docket Number: KLA1P067/P995

Total Fees Authorized:

Digital Certificate Holder: cn=Russell Nicholas Swerdon.,ou=Registered Attorneys,ou=Patent and Trademark Office,ou=Department of Commerce,o=U.S. Government,c=US  
Certificate Message Digest: e657524a0566a2027cdc9d06f5e337bbe4d9ba44



## TRANSMITTAL

Electronic Version v1.1  
Stylesheet Version v1.1.0

Title of Invention	METHOD AND APPARATUS USING INTERFEROMETRIC METROLOGY FOR HIGH ASPECT RATIO INSPECTION	
Application Number:	10/672298	
Date:	2004-02-25	
First Named Applicant:	Shiow-Hwei Hwang	
Confirmation Number:	4459	
Attorney Docket Number:	KLA1P067/P995	
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Submitted by:	Elec. Sign.	Sign. Capacity
Mr. Russell N. Swerdon Registered Number: 36,943	RUSSELL N. SWERDON	Attorney
Documents being submitted us-ids	Files KLA1P067-usidst.xml us-ids.dtd us-ids.xsl	
Comments		



## ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	METHOD AND APPARATUS USING INTERFEROMETRIC METROLOGY FOR HIGH ASPECT RATIO INSPECTION						
Application Number: 10/672298 Confirmation Number: 4459 First Named Applicant: Shiow-Hwei Hwang Attorney Docket Number: KLA1P067/P995 Art Unit: 2621 Search string: ( 4818110 or 6262818 or 6078392 ).pn.							
<b>US Patent Documents</b>							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	4818110	1989-04-04	Davidson		356	358
	2	6262818	2001-07-17	Cuche et al.		359	9
	3	6078392	2000-06-20	Thomas et al.		356	457
<b>Signature</b>							
Examiner Name					Date		